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| U.S. Patent and Trademark Office<br><br><b>INFORMATION DISCLOSURE<br/>STATEMENT</b><br><br>(Use several sheets if necessary) | Attorney Docket No.: UMC-96-279              | Serial No.: <del>Not Assigned</del><br>08/958, 460 |
|  | Applicants: Chih-Chien Liu, et al.           |  |
|  | Filing Date: <del>Herewith</del><br>10/28/97 | Art Group: <del>Not Assigned</del><br>1700         |

**U.S. PATENT DOCUMENTS**

| Examiner<br>Initial |  | Document Number | Date | Name | Class | Sub-<br>Class | Filing<br>Date if<br>Appro-<br>priate |
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**FOREIGN PATENT DOCUMENTS**

|  |  | Document Number | Date | Country | Class | Sub-<br>Class | Trans-<br>lation<br>Yes/No |
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|  |  |                 |      |         |       |               |                            |
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**OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)**

|    |  |  |  |
|----|--|--|--|
| RA |  |  | J.T. Pye, et al., "High-Density Plasma CVD and CMP for 0.25- $\mu$ m Intermetal Dielectric Processing," Solid State Technology, December 1995, pp.65-69. |
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EXAMINER

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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.